In the Claims

1	1. (currently amended) A device for depositing a film onto a surface of a substrate
2	having a circular profile, comprising:
3	a film material source for dispersing film material incident in the general direction of the
4	substrate surface; and
5	at least one collimator between the film material source and the substrate, the at least one
6	collimator having circularly spaced sheets establishing passages through said collimator, the
7	passages being circular and angled in a radial direction relative to the circular profile of the
8	substrate therein, wherein the passages are angled obliquely relative to the substrate surface such
9	that incident film material traveling toward the substrate in a trajectory which is not substantially
10	parallel to the oblique angle of the passages is blocked.
1	2. (canceled)
1	3. (canceled)
1	4. (original) The device in accordance with claim 1, wherein a ratio of the height of the
2	passages to the depth of the passages is substantially uniform throughout the collimator.
1	5. (currently amended) The device in accordance with claim [[2]] 1, wherein the angle
2	of the passages with respect to the substrate surface of the sheet of the collimator can be varied
3	from about 0 to about 90°.

1	6. (original) The device in accordance with claim 1 wherein the film material source is a
2	target constructed of the film material and particles are ejected from the target material by a
3	sputtering technique.
1	7. (original) The device in accordance with claim 1 wherein the film material source is
2	an evaporation medium constructed of the film material and particles are dispersed from the
3	evaporation medium in an evaporation technique.
1	8. (original) The device in accordance with claim 1, wherein the collimator can be
2	electrically floating, on earth or biasing.
1	9. (original) The device in accordance with claim 1, wherein the collimator comprises a
2	material selected from the group consisting of a conductor material, an insulator material, or a
3	semiconductor material.
1	10. (currently amended) The device in accordance with claim 1 wherein the collimator
2	comprises:
3	a support structure [[;]] comprising a plurality of second sheets placed radially
4	with respect to the center of the collimator, the plurality of second sheets being held in relative
5	relation by the combination of the circularly spaced sheets and the second sheets, the
6	combination support structure and forming passages there between.

- 1 11. (new) A device for depositing a film onto a surface of a substrate having a circular 2 profile, comprising: 3 a film material source for dispersing film material incident in the general direction of the substrate surface; 4 5 at least one collimator between the film material source and the substrate, the at least one 6 collimator having radially spaced sheets establishing passages through said collimator, the sheets 7 are angled obliquely relative to the substrate surface such that incident film material traveling toward the substrate in a trajectory which is not substantially parallel to the oblique angle of the 8 9 sheets is blocked
- 1 12. (new) The device in accordance with claim 11, further comprising at least one substantially circular sheet being circular with respect to the radially spaced sheets, the substantially circular sheet being interposed with the radially spaced sheets forming passages therebetween.
- 1 13. (new)The device in accordance with claim 12, wherein the at least one 2 substantially circular sheet is angled obliquely relative to the substrate surface.